

REMARKS

This application has been reviewed in light of the Office Action dated August 31, 2004. Claims 7-10 are presented for examination. Claim 7 has been amended to define still more clearly what Applicants regard as their invention. New Claim 10 has been added to provide Applicants with a more complete scope of protection.^{1/} Claim 7 is in independent form. Favorable reconsideration is requested.

In the Office Action, Claims 7-9 were rejected under the judicially-created doctrine of obvious-type double patenting as being unpatentable over Claims 1 and 4 of U.S. Patent 6,661,179 (*Aoki et al.*), issued on the parent of this application.

As amended, independent Claim 7 recites:

“7. A manufacturing method of an electron source panel having a plurality of electron emitting devices disposed on a substrate, comprising the steps of:
measuring electron emission characteristics of each of the electron emitting devices and setting a characteristics adjustment target value;
applying a plurality of characteristics shift voltages having discrete values to some of the electron emitting devices, measuring electron emission characteristics of these electron emitting devices and creating a characteristics adjustment table in accordance with change rates of measured electron emission characteristics of these electron emitting devices; and
selecting a predetermined characteristics shift voltage value from the plurality of characteristics shift voltage values by referring to the characteristics adjustment table created for each of the electron emitting devices and applying the predetermined characteristics shift voltage to the electron emitting devices to shift the characteristics toward the characteristics adjustment target value.”

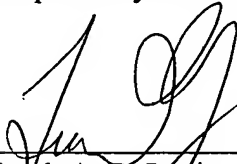
^{1/} The subject matter of Claim 10 is supported in the specification as originally filed, at least from page 40, line 26 to page 41, line 2.

Thus, Claim 7, as well as Claims 8-10 dependent thereon, recite a manufacturing method of an electron source panel having a plurality of electron emitting devices disposed on a substrate. Claims 1 and 4 of *Aoki et al.*, on the other hand, recite a *characteristics adjustment method* for a multi electron source having plural electron emitting devices disposed on a substrate. For at least these reasons, it is believed that Claims 7-10 are patentably distinguishable over Claims 1 and 4 of *Aoki et al.* Accordingly, withdrawal of the double patenting rejection is respectfully requested.

In view of the foregoing amendments and remarks, Applicants respectfully request favorable reconsideration and early passage to issue of the present application.

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our below listed address.

Respectfully submitted,



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